

TYPICAL PHOTOLITHOGRAPHY  
RESIST APPLY/EXPOSE CELL

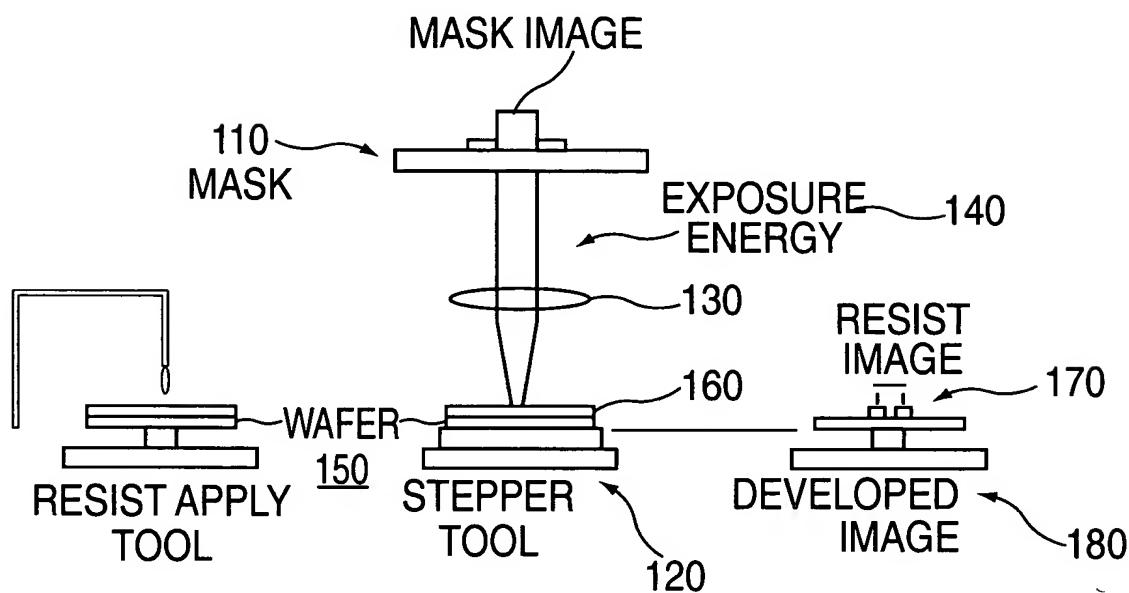


FIG. 1

TYPICAL RESIST  
SUPPLY SYSTEM

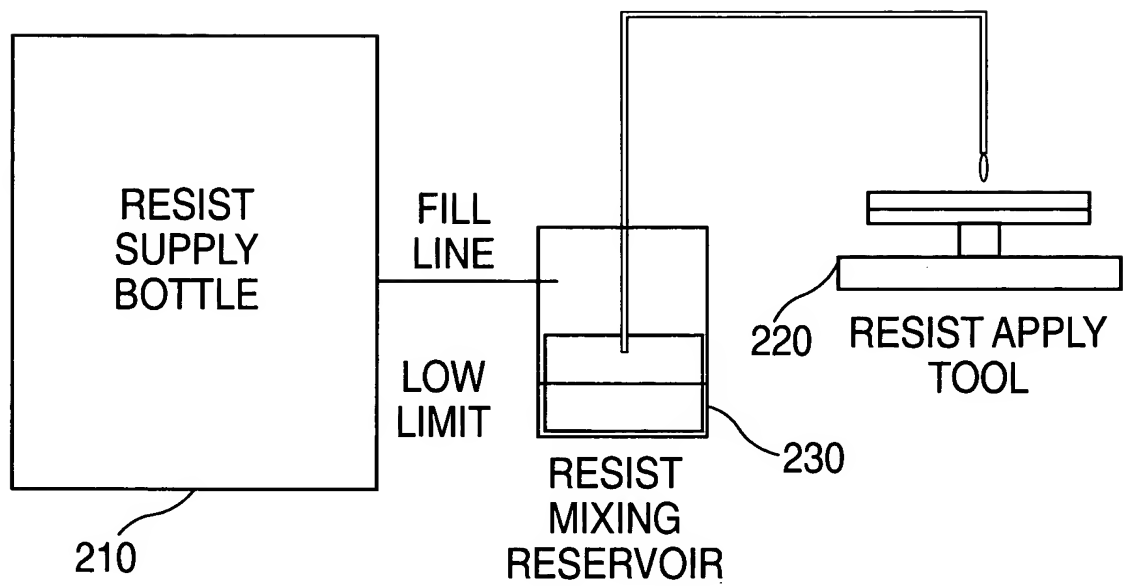
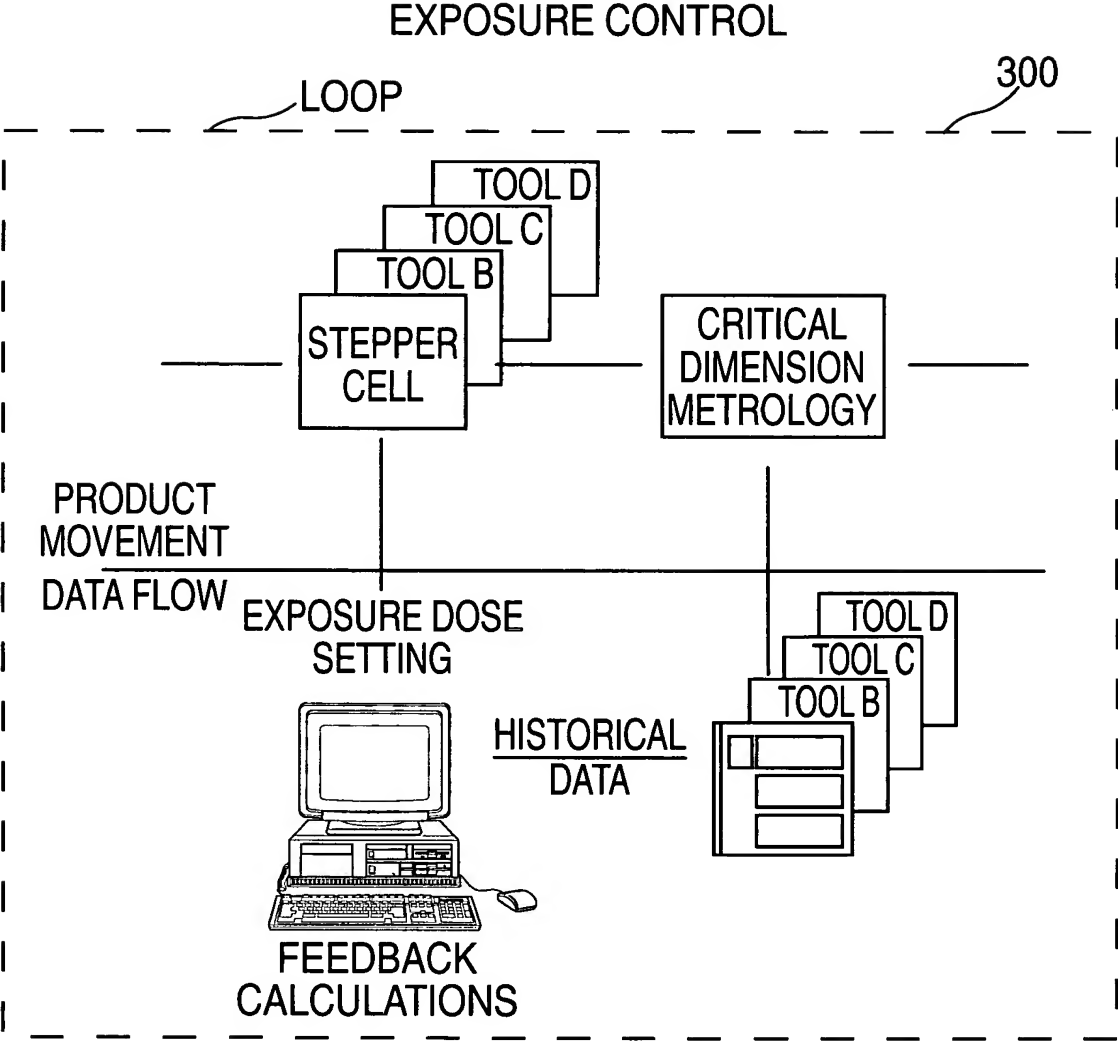


FIG. 2



**FIG. 3**  
(PRIOR ART)

## EXPOSURE CONTROL LOOP WITH BATCH FACTOR ADJUSTMENTS

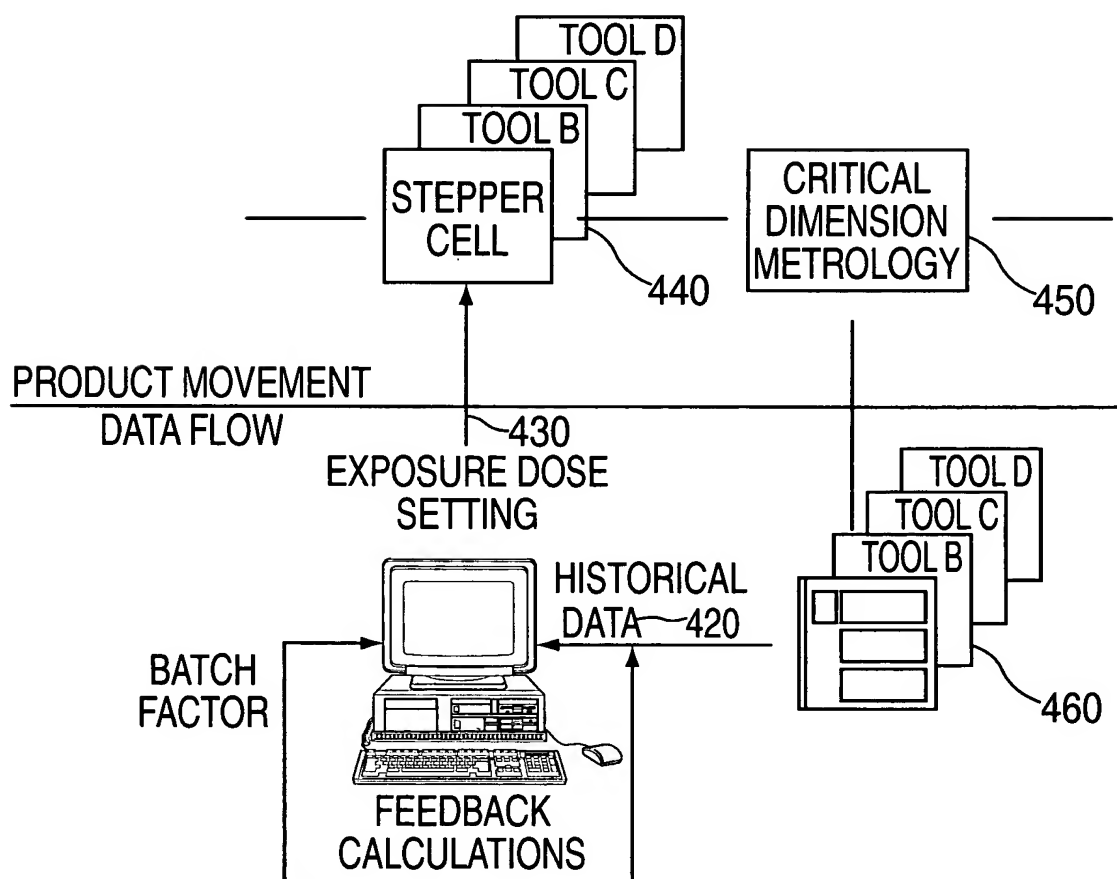


FIG. 4

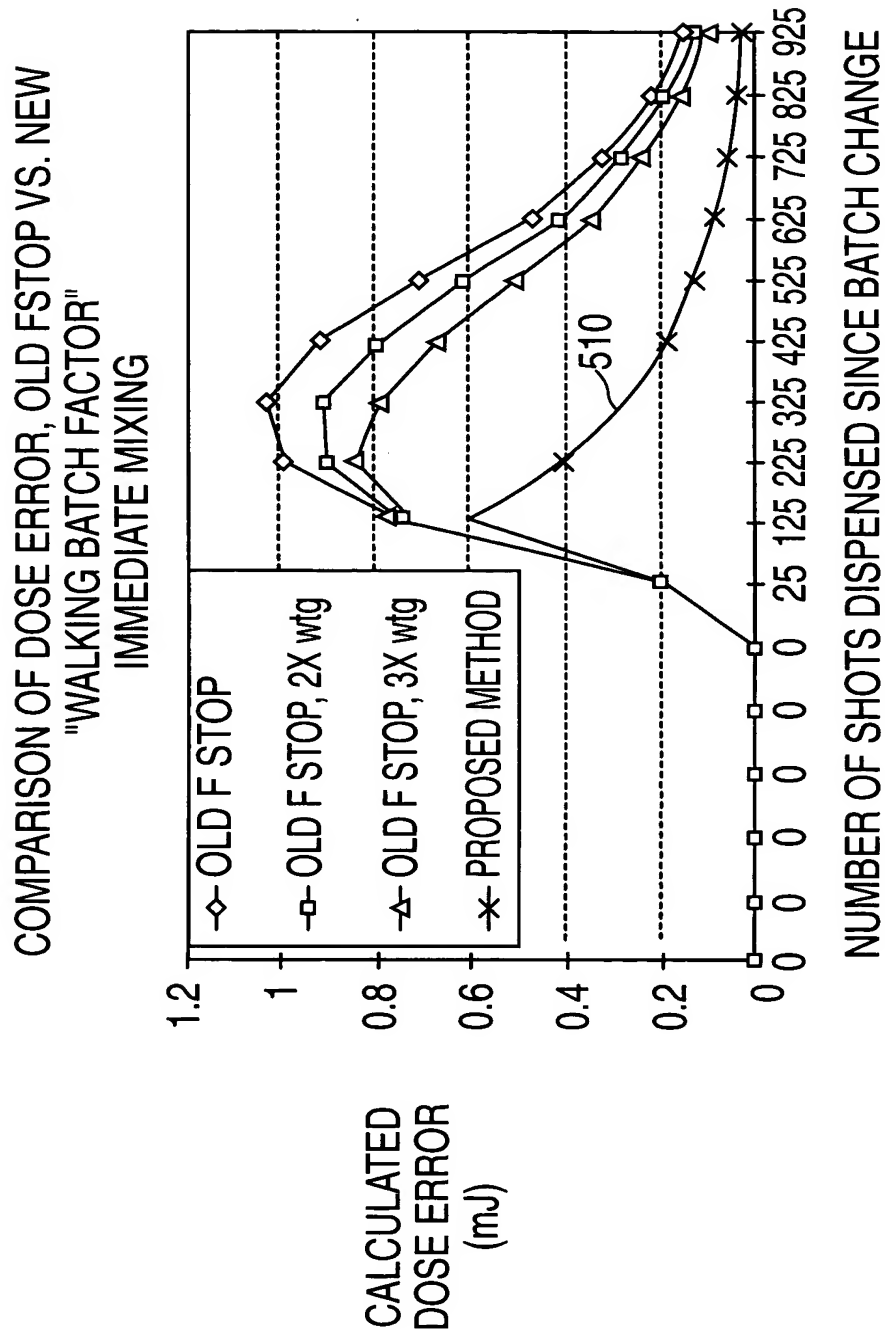


FIG. 5

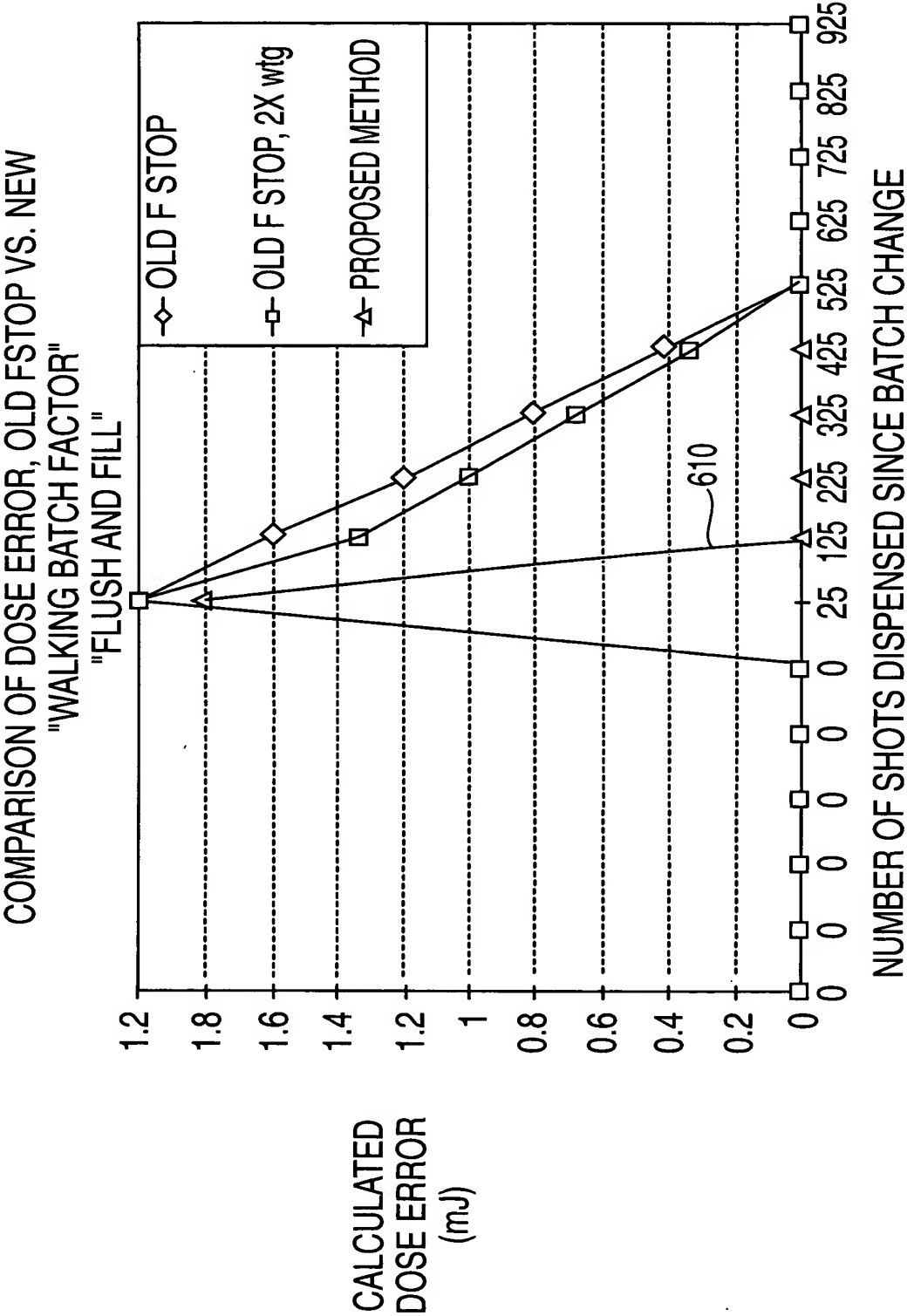


FIG. 6